Special Issue

Machine Learning/Deep Learning in Medical Image Processing

Message from the Guest Editor

This special issue focuses on application of machine learning/deep learning for medical images. We welcome original papers and review papers related with the following topics. Although this special issue focuses on machine learning/deep learning, papers of medical image processing with other techniques are also welcomed. Research Topics:

- Cutting-edge methodology/algorithm of machine learning/deep learning for medical images
- Clinical application of machine learning/deep learning for medical images
- Open source software of machine learning/deep learning which are used for medical image processing
- Open data of medical images which are useful for development and validation of machine learning/deep learning
- Reproducibility/validation study of open source software of machine learning/deep learning for medical images

Guest Editor

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Deadline for manuscript submissions

closed (30 April 2021)



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About the Journal

Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multidimensional network.

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